

Attorney Docket No. c-6-us

c-6-us.tri

**These documents are being hand-delivered on or about 5/8/97**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Title: PROBE CARD ASSEMBLY AND KIT, AND METHODS OF USING SAME

Inventor(s): Eldridge, et al.

Serial No.: 08/554,902

Examiner: Goins, C.

Filing Date: 11/09/95

Art Unit: 3206

To: Commissioner of Patents and Trademarks  
Washington, DC 20231

**RECEIVED**

**MAY 08 1997**

**GROUP 3200**

**TRANSMITTAL**

Enclosed herewith is:

- SUPPLEMENTAL INFORMATION DISCLOSURE (6)
- SUPPLEMENTAL INFORMATION DISCLOSURE (7)
- SUPPLEMENTAL INFORMATION DISCLOSURE (8)
- copies of references
  
- SUPPLEMENTAL DECLARATION


The most recent action in this case was an Office action requiring restriction or election, to which a response was filed on 4/4/97.

These Supplemental Information Disclosure Citations are being hand-delivered, prior to an action on the merits. **NO FEE IS REQUIRED**

If it is determined that a fee is required, the three Supplemental Information Disclosure Citations enclosed herewith should be treated as ONE Information Disclosure Citation.

Charge any shortfall to Dep. Acct. 12-1445

For the Applicant,

  
Gerald E. Linden 30,282  
(407) 382-7966

5/7/97  
date

Attorney Docket No. c-6-us

c-6-us.id6

#8  
5/9/97  
JD

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Title: PROBE CARD ASSEMBLY AND KIT, AND METHODS OF USING SAME

Inventor(s): Eldridge, et al.

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SUPPLEMENTAL INFORMATION DISCLOSURE CITATION

(Substitute PTO-1449)

This SUPPLEMENTAL INFORMATION DISCLOSURE CITATION (6) is being provided in addition to:

- (1) INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (2) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (3) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (4) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (5) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 7/17/96

Although not required, TITLES for the patent references are provided herewith, as an aid to the examiner.

-----  
Attention is directed to the following commonly-owned patents,  
copies of which are enclosed herewith:

<u>5,476,211</u>	<u>Khandros; 12/95</u>	<u>228/180.5</u>
METHOD OF MANUFACTURING ELECTRICAL CONTACTS, USING A SACRIFICIAL MEMBER		

<u>5,601,740</u>	<u>Eldridge, et al.; 2/97</u>	<u>219/130.4</u>
METHOD AND APPARATUS FOR WIREBONDING, FOR SEVERING BOND WIRES, AND FOR FORMING BALLS ON THE ENDS OF BOND WIRES		

## SOURCES OF THE REFERENCES

This SUPPLEMENTAL INFORMATION DISCLOSURE CITATION lists references cited in the International Search Reports pertaining to various commonly-owned, copending PCT applications. All the references listed in the Search Reports are listed herein. However, if the references have previously been disclosed, only the patent number is listed.

The references presented herein are arranged in "groups", as follows:

GROUP 1. These references were cited in:

  x   the International Search Report  
      the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08328 filed 28 May 96. [C-8-PCT]

      copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

  x   copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/602,179 filed 15 Feb 96. [C-8-US]

GROUP 1A. These references were cited in an Office action pertaining to commonly-owned, copending 08/602,179 filed 15 Feb 96 [C-8-US]

GROUP 2. These references were cited in:

  x   the International Search Report  
      the Written Opinion

pertaining to commonly-owned, copending PCT/US96/07924 filed 24 May 96. [C-9-PCT]

      copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

  x   copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/340,144 filed 15 Nov 94 [C-2-US]

GROUP 3. These references were cited in:

  x   the International Search Report  
  x   the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08275 filed 28 May

96. [C-11-PCT]

\_\_\_ copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

x copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/749,111 filed 14 Nov 96.  
[C-11-US]

GROUP 4. These references were cited in:

x the International Search Report  
\_\_\_ the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08117 filed 24 May 96. [C-12-PCT]

\_\_\_ copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

x copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/789,147 filed 24 Jan 97.  
[C-12-US]

GROUP 4A. References located in a recent search pertaining to comonly-owned, copending U.S. Patent Application No. 08/789,147 filed 24 Jan 97. [C-12-US]  
NOTE: THESE REFERENCES ARE THE SAME AS IN GROUP 5A

GROUP 5. These references were cited in:

x the International Search Report  
\_\_\_ the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08107, filed 24 May 96. [C-14-PCT]

\_\_\_ copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

x copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/788,740 filed 24 Jan 97.  
[C-14-US]

GROUP 5A. References located in a recent search

pertaining to comonly-owned, copending U.S. Patent Application No. 08/788,740 filed 24 Jan 97 [C-14-US]

GROUP 6. These references were cited in:

  x   the International Search Report

       the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08274, filed 28 May 96. [C-15-PCT]

       copies of these references are enclosed herewith, except for copies of references previously submitted to the Patent Office;

  x   copies of these references are NOT enclosed herewith, but have (i) previously been disclosed or (ii) will be supplied to the file of commonly-owned, copending U.S. Patent Application No. 08/779,020 filed 10 Feb 97. [C-15-US]

GROUP 7. These references were cited in:

  x   the International Search Report

       the Written Opinion

pertaining to commonly-owned, copending PCT/US96/08276, filed 28 May 96. [C-16-PCT]

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GROUP 8A. These references were found in a database search.

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GROUP 1: PCT/US96/08328, filed 28 May 96 [C-8-PCT]

<u>5,414,298</u>	<u>Grube, et al.; 5/95</u>	<u>257/690</u>
SEMICONDUCTOR CHIP ASSEMBLIES AND COMPONENTS WITH PRESSURE CONTACT <b>PREVIOUSLY DISCLOSED</b>		
<u>3,842,189</u>	<u>Southgate; 10/74</u>	<u>174/52 S</u>
CONTACT ARRAY AND METHOD OF MAKING THE SAME <b>PREVIOUSLY DISCLOSED</b>		
<u>5,346,861</u>	<u>Khandros, et al.; 9/94</u>	<u>437/209</u>
SEMICONDUCTOR CHIP ASSEMBLIES AND METHODS OF MAKING SAME <b>PREVIOUSLY DISCLOSED</b>		
<u>5,230,632</u>	<u>Baumberger, et al.; 7/93</u>	<u>439/66</u>
DUAL ELEMENT ELECTRICAL CONTACT AND CONNECTOR ASSEMBLY UTILIZING SAME		

GROUP 1A: 08/602,179 filed 15 Feb 96 [C-8-US]

<u>5,239,447</u>	<u>Cotues, et al.; 8/93</u>	<u>361/744</u>
STEPPED ELECTRONIC DEVICE PACKAGE <b>PREVIOUSLY DISCLOSED</b>		
<u>5,310,702</u>	<u>Yoshida, et al.; 5/94</u>	<u>437/211</u>
METHOD OF PREVENTING SHORT-CIRCUITING OF BOND WIRES		
<u>5,481,241</u>	<u>Caddock, Jr.; 1/96</u>	<u>338/51</u>
FILM-TYPE HEAT SINK-MOUNTED POWER RESISTOR COMBINATION HAVING ONLY A THIN ENCAPSULANT, AND HAVING AN ENLARGED INTERNAL HEAT SINK		
<u>4,132,341</u>	<u>Bratschun; 1/79</u>	<u>228/122</u>
HYBRID CIRCUIT CONNECTOR ASSEMBLY		
<u>5,294,039</u>	<u>Pai, et al.; 3/94</u>	<u>228/180.22</u>
PLATED COMPLIANT LEAD <b>PREVIOUSLY DISCLOSED</b>		
<u>5,346,861</u>	<u>Khandros, et al.;</u>	<u>437/209</u>
SEMICONDUCTOR CHIP ASSEMBLIES AND METHODS OF MAKING SAME <b>PREVIOUSLY DISCLOSED</b>		
<u>Jap. 57-152137 9/82 Saeki (56-35430)</u>		<u>437/209</u>
SEMICONDUCTOR PACKAGE AND MANUFACTURE THEREOF		
<u>Jap. 56-26446 3/81 Nakatani (54-101710)</u>		<u>437/209</u>
SEMICONDUCTOR DEVICE		

GROUP 2: PCT/US96/07924, filed 24 May 96 [C-9-PCT]

<u>3,214,563</u>	<u>Ford; 10/65</u>	<u>219/69</u>
ELECTRICAL DRILLING		
<u>4,829,153</u>	<u>Correy; 5/89</u>	<u>219/130.4</u>
WELDING ARC INITIATOR		
<u>5,006,688</u>	<u>Cross; 4/91</u>	<u>219/130.4</u>
LASER-ARC APPARATUS AND METHOD FOR CONTROLLING PLASMA CLOUD		
<u>5,095,187</u>	previously disclosed to PTO	

GROUP 3: PCT/US96/08275, filed 28 May 96 [C-11-PCT]

<u>3,636,242</u>	<u>Hansson; 1/72</u>	<u>174/128</u>
AN ELECTRIC CONDUCTOR WIRE		
<u>4,537,808</u>	<u>Yamamoto, et al.; 8/85</u>	<u>428/36</u>
ELECTRICALLY CONDUCTIVE COMPOSITE MATERIAL		
<u>5,045,410</u>	<u>Hiesbock, et al.; 9/91</u>	<u>428/644</u>
LOW PHOSPHOROUS CONTAINING BAND-SHAPED AND/OR FILAMENTARY MATERIAL		
<u>4,354,310</u>	<u>Hatton; 10/82</u>	<u>29/605</u>
METHOD OF MAKING INDUCTANCE		
<u>4,025,143</u>	<u>Rozmus; 5/77</u>	<u>339/278C</u>
ELECTRICAL CONTACTS		
<u>5,059,143</u>	<u>Grabbe; 10/91</u>	<u>439/886</u>
CONNECTOR CONTACT		
<u>5,129,143</u>	<u>Wei, et al.; 7/92</u>	<u>29/885</u>
DURABLE PLATING FOR ELECTRICAL CONTACT TERMINALS		
<u>5,163,835</u>	<u>Morlion, et al.; 11/92</u>	<u>439/67</u>
CONTACT ASSEMBLY WITH GROUNDING CONTACT SUPPORT		
<u>5,090,119</u>	<u>Tsuda, et al.; 2/92</u>	<u>29/843</u>
METHOD OF FORMING AN ELECTRICAL CONTACT BUMP		
<u>5,172,851</u>	<u>Matsushita, et al.; 12/92</u>	<u>228/179</u>
METHOD OF FORMING A BUMP ELECTRODE AND MANUFACTURING A RESIN-ENCAPSULATED SEMICONDUCTOR DEVICE		

GROUP 4: PCT/US96/08117, filed 24 May 96 [C-12-PCT]

see PCT search report

IBM Technical Disclosure Bulletin, Vol. 21, No. 8, January  
TEXT PROBE CONTACT GRID TRANSLATOR BOARD

IBM Technical Disclosure Bulletin, Vol. 21, No. 4, Sept. 1978  
AUTOMATIC TEST EQUIPMENT TRANSLATOR BOARD

IBM Technical Disclosure Bulletin, Vol. 17, No. 2, July 1974  
MULTIPOINT TEST PROBE FOR PRINTED CARDS

JP A 54-146581  
ELECTRIC CHARACTERISTIC MEASURING DEVICE FOR SEMICONDUCTOR  
CHIP

4,998,885                      Beaman; 3/91                      439/66  
ELASTOMERIC AREA ARRAY INTERPOSER

4,899,106                      Ogura; 2/90                      324/158 F  
PERSONALITY BOARD

4,724,383                      Hart; 2/88                      324/158 F  
PC BOARD TEST FIXTURE

4,528,500                      Lightbody, et al.; 7/85                      324/73 PC  
APPARATUS AND METHOD FOR TESTING CIRCUIT BOARDS

4,508,405                      Damon, et al.; 4/85                      339/75 MP  
ELECTRONIC SOCKET HAVING SPRING PROBE CONTACTS

4,357,062                      Everett; 11/82                      339/18 R  
UNIVERSAL CIRCUIT BOARD TEST FIXTURE

GROUP 4A:    **See GROUP 5A hereinbelow**

GROUP 5: PCT/US96/08107, filed 24 May 96 [C-14-PCT]

5,476,211 (See above. commonly-owned patent)

Jap. 3-279370; Otsuka; 9/92 (4-355940)  
JOINING METHOD FOR TAB INNER LEAD AND BONDING TOOL FOR  
JUNCTION

Jap. 63-221924; Hokari; 8/90 (2-69940)  
SEMICONDUCTOR INTEGRATED CIRCUIT BONDING PAD CONFIGURATION

GROUP 5A: USSN 08/788,740, filed 24 Jan 97

5,569,272                      Reed, et al.; 10/96                      606/151  
TISSUE-CONNECTIVE DEVICES WITH MICROMECHANICAL BARBS

5,393,375                      MacDonald, et al.; 2/95                      156/643



PROCESS FOR FABRICATING SUBMICRON SINGLE CRYSTAL  
ELECTROMECHANICAL STRUCTURES

5,373,627 Grebe; 12/94 29/841  
METHOD OF FORMING MULTI-CHIP MODULE WITH HIGH DENSITY  
INTERCONNECTIONS

5,312,456 Reed, et al.; 5/94 411/456  
MICROMECHANICAL BARB AND METHOD FOR MAKING SAME

5,278,442 Prinz, et al.; 1/94 257/417  
ELECTRONIC PACKAGES AND SMART STRUCTURES FORMED BY THERMAL  
SPRAY DEPOSITION

5,258,097 Mastrangelo; 11/93 156/644  
DRY-RELEASE METHOD FOR SACRIFICIAL LAYER MICROSTRUCTURE  
FABRICATION

5,236,118 Bower, et al.; 8/93 228/193  
ALIGNED WAFER BONDING

4,953,834 Ebert, et al.; 9/90 267/160  
PENDULUM WITH BENDING SPRING JOINT

4,918,032 Jain, et al.; 4/90 437/228  
METHOD FOR FABRICATING THREE-DIMENSIONAL MICROSTRUCTURES AND  
A HIGH SENSITIVITY VIBRATION SENSOR USING SUCH  
MICROSTRUCTURES

4,740,410 Muller, et al.; 4/88 428/133  
MICROMECHANICAL ELEMENTS AND METHODS FOR THEIR FABRICATION

4,522,893 Bohlen, et al.; 6/85 428/641  
CONTACT DEVICE FOR RELEASABLY CONNECTING ELECTRICAL COMPONENTS

GROUP 6: PCT/US96/08274, filed 28 May 96 [C-15-PCT]

5,476,211 (See above. commonly-owned patent)

4,674,671 Fister, et al.; 6/87 228/111  
THERMOSONIC PALLADIUM LEAD WIRE BONDING

2,429,222 Erhardt, et al.; 10/47 29/885  
METHODS OF MAKING CONTACT WIRES

5,228,862 Baumberger, et al.; 7/93 439/66  
FLUID PRESSURE ACTUATED CONNECTOR

5,294,039 previously disclosed

GROUP 7: PCT/US96/08276, filed 28 May 96 [C-16-PCT]

5,476,211 (See above. commonly-owned patent)

4,674,671            Fister, et al.; 6/87            228/111  
THERMOSONIC PALLADIUM LEAD WIRE BONDING

5,495,667            Farnworth, et al.; 3/96            29/843  
METHOD FOR FORMING CONTACT PINS FOR SEMICONDUCTOR DICE AND  
INTERCONNECTS (note: filing date is 07 Nov 94)

2,429,222            Erhardt, et al.; 10/47            29/885  
METHODS OF MAKING CONTACT WIRES

5,294,039            previously disclosed

GROUP 8A: Database Search

PCT/US95/07901 Fjelstad, et al.; 6/95  
(earliest priority date is 6/95)  
MICROELECTRONIC CONTACTS AND ASSEMBLIES

PCT/US95/09201 DiStefano, et al.; 7/95  
(earliest priority date is 7/94)  
ELECTRICAL CONNECTIONS WITH DEEFORMABLE CONTACTS

PCT/US95/11933 Kovac, et al.; 9/95  
(earliest priority date is 9/94)  
COMPLIANT INTERFACE FOR A SEMICONDUCTOR CHIP

PCT/US96/06228 Fjelstad, et al.; 5/96  
(earliest priority date is 5/94)  
FABRICATION OF LEADS ON SEMICONDUCTOR CONNECTION COMPONENTS

5,548,091            DiStefano, et al.; 8/96            174/260  
SEMICONDUCTOR CHIP CONNECTION COMPONENTS WITH ADHESIVES AND  
METHODS FOR BONDING TO THE CHIP (filed 10/93)

5,557,501            DiStefano, et al.; 9/96            361/704  
COMPLIANT THERMAL CONNECTORS AND ASSEMBLIES INCORPORATING THE  
SAME (filed Nov. 18, 1994)

5,597,470            Karavakis, et al.; 1/97            205/118  
METHOD FOR MAKING A FLEXIBLE LEAD FOR A MICROELECTRONIC DEVICE  
(filed 6/95)

5,590,460            DiStefano, et al.; 1/97            29/830  
METHOD OF MAKING MULTILAYER CIRCUIT (filed 7/94)

5,536,909            DiStefano, et al.; 7/96            174/261  
SEMICONDUCTOR CONNECTION COMPONENTS AND METHODS WITH  
RELEASABLE LEAD SUPPORT (continuation of 919,772 filed 7/92)

5,558,928      DiStefano, et al.; 9/96      428/209  
MULTI-LAYER CIRCUIT STRUCTURES, METHODS OF MAKING SAME AND  
COMPONENTS FOR USE THEREIN (division of 815,401 filed 12/91)

5,570,504      DiStefano, et al.; 11/96      29/830  
MULTI-LAYER CIRCUIT CONTSTRUCTION METHOD AND STRUCTURE  
(division of 816,634 filed 12/91)

5,558,321      DiStefano, et al.; 12/96      174/264  
MULTI-LAYER CIRCUIT CONSTRUCTION METHODS AND STRUCTURES WITH  
CUSTOMIZATION FEATURES AND COMPONENTS FOR USE THEREON  
(division of 816,634 filed 12/92)

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**SUPPLEMENTAL INFORMATION DISCLOSURE CITATION GROUP 3200**  
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- (4) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (5) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 7/17/96
- (6) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed herewith

Although not required, TITLES for the patent references are provided herewith, as an aid to the examiner.

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5,476,211                      Khandros; 12/95                      228/180.5  
METHOD OF MANUFACTURING ELECTRICAL CONTACTS, USING A  
SACRIFICIAL MEMBER

5,601,740                      Eldridge, et al.; 2/97                      219/130.4  
METHOD AND APPARATUS FOR WIREBONDING, FOR SEVERING BOND WIRES,  
AND FOR FORMING BALLS ON THE ENDS OF BOND WIRES

### SOURCE OF THE REFERENCES

This SUPPLEMENTAL INFORMATION DISCLOSURE CITATION lists United States Patent No. 5,495,667 and "references cited" therein. Please take note that USP 5,495,667 was filed on November 7, 1994.

\_\_\_ Copies of the references cited herein are enclosed herewith.

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/340,144 [C-2-US].

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#### U.S. Patent References:

5,495,667                      Farnworth, et al.; 3/96                      29/843  
METHOD FOR FORMING CONTACT PINS FOR SEMICONDUCTOR DICE AND  
INTERCONNECTS    (filing date of this patent is 07 Nov 94)

5,366,589                      Chang; 11/94                      156/657  
BONDING PAD WITH CIRCULAR EXPOSED AREA AND METHOD THEREOF

5,302,891                      Wood, et al.; 4/94                      324/158 F  
DISCRETE DIE BURN-IN FOR NON-PACKAGED DIE

5,293,073                      Ono; 3/94                      257/740  
ELECTRODE STRUCTURE OF A SEMICONDUCTOR DEVICE WHICH USES  
COPPER WIRE AS A BONDING WIRE

5,266,912                      Kledzik; 11/93                      333/247  
INHERENTLY IMPEDANCE MATCHED MULTIPLE INTEGRATED CIRCUIT  
MODULE

4,877,173                      Fujimoto, et al.; 10/89                      228/1.1  
WIRE BONDING APPARATUS

4,873,123                      Canestaro, et al.; 10/89                      427/96  
FLEXIBLE ELECTRICAL CONNECTOIN AND METHOD OF MAKING SAME

4,434,347                      Kurtz, et al.; 2/84                      219/56.22  
LEAD FRAME WIRE BONDING BY PREHEATING

4,060,828                      Satonaka; 11/77                      357/71  
SEMICONDUCTOR DEVICE HAVING MULTI-LAYER STRUCTURE WITH  
ADDITIONAL THROUGH-HOLE INTERCONNECTION

3,894,671                      Kulicke, Jr., et al.; 7/75                      228/4.5  
SEMICONDUCTOR WIRE BONDER

3,381,081            Schalliol; 4/68            174/68.5  
ELECTRICAL CONNECTION AND METHOD OF MAKING THE SAME

3,266,137            DeMille, et al.; 8/66            29/473.1  
METAL BALL CONNECTION TO CRYSTALS

3,227,933            Punte, et al.; 1/66            317/234  
DIODE AND CONTACT STRUCTURES

3,006,067            Anderson, et al.; 10/61            29/470  
THERMO-COMPRESSION BONDING OF METAL TO SEMICONDUCTORS AND THE  
LIKE

Foreign Patent References

58-9330            Japan; 1/83            437/8

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- (4) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 4/4/96
- (5) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed 7/17/96
- (6) SUPPLEMENTAL INFORMATION DISCLOSURE CITATION, filed herewith
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### GROUP 1

x Copies of the references cited herein are enclosed herewith.

     Copies of the references cited herein may be located in the file of commonly-owned, copending 08/554,902 [C-6-US]

### U.S. Patent References:

<u>5,461,327</u> PROBE APPARATUS	<u>Shibata et al.; 10/95</u>	<u>324/760</u>
<u>5,436,571</u> PROBING TEST METHOD OF CONTACTING A PLURALITY OF PROBES OF A PROBE CARD WITH PADS ON ACHIP ON A SEMICONDUCTOR WAFER	<u>Karasawa; 7/95</u>	<u>324/765</u>
<u>5,422,579</u> METHOD OF IDENTIFYING PROBE POSITION AND PROBING METHOD IN PROBER	<u>Yamaguchi; 6/95</u>	<u>324/758</u>
<u>5,412,329</u> PROBE CARD	<u>Iino et al.; 5/95</u>	<u>324/754</u>
<u>5,410,259</u> PROBING DEVICE SETTING A PROBE CARD PARALLEL	<u>Fujihara et al.; 4/95</u>	<u>324/758</u>
<u>5,399,983</u> PROBE APPARATUS	<u>Nagasawa; 3/95</u>	<u>324/758</u>
<u>5,378,971</u> PROBE AND A METHOD OF MANUFACTURING THE SAME	<u>Yamashita; 1/95</u>	<u>324/760</u>
<u>5,325,052</u> PROBE APARATUS	<u>Yamashita; 6/94</u>	<u>324/158P</u>
<u>5,321,453</u> PROBE APPARATUS FOR PROBING AN OBJECT HELD ABOVE THE PROBE CARD	<u>Mori et al.; 6/94</u>	<u>324/158 P</u>
<u>5,321,352</u> PROBE APARATUS AND METHOD OF ALIGNMENT FOR THE SAME	<u>Takebuchi; 6/94</u>	<u>324/158 F</u>



<u>5,278,494</u>	<u>Obigane; 1/94</u>	<u>324/158 F</u>
WAFER PROBING TEST MACHINE		
<u>5,266,895</u>	<u>Yamashita; 11/93</u>	<u>324/158 P</u>
PROBE WITH CONTACT PORTION INCLUDING AU AND CU ALLOY		
5,220,279		
<u>5,198,755</u>	<u>Ikeda et al.; 3/93</u>	<u>324/158 P</u>
PROBE APPARATUS		
<u>5,172,053</u>	<u>Itoyama; 12/92</u>	<u>324/158 F</u>
PROBER APPARATUS		
<u>5,166,603</u>	<u>Hoshi; 11/92</u>	<u>324/158 P</u>
PROBE METHOD		
<u>5,151,651</u>	<u>Shibata; 9/92</u>	<u>324/158 P</u>
APPARATUS FOR TESTING IC ELEMENTS		
<u>5,126,662</u>	<u>Jinbo; 6/92</u>	<u>324/158 P</u>
METHOD OD TESTING A SEMICONDUCTOR CHIP		
<u>5,113,132</u>	<u>Hoshi; 6/92</u>	<u>324/158 F</u>
PROBING METHOD		
<u>5,091,694</u>	<u>Ikeda et al.; 2/92</u>	<u>324/158 P</u>
QUARTZ PROBE APPARATUS		
<u>5,091,692</u>	<u>Ohno et al.; 2/92</u>	<u>324/158 F</u>
PROBING TEST DEVICE		
<u>5,086,270</u>	<u>Karasawa et al.; 2/92</u>	<u>324/158 P</u>
PROBE APPARATUS		
<u>5,061,894</u>	<u>Ikeda; 10/91</u>	<u>324/158 F</u>
PROBE DEVICE		
<u>5,034,684</u>	<u>Mitsui et al.; 7/91</u>	<u>324/158 F</u>
PROBE DEVICE AND METHOD OF CONTROLLING THE SAME		
<u>4,998,062</u>	<u>Ikeda; 3/91</u>	<u>324/158 F</u>
PROBE DEVICE HAVING MICRO-STRIP LINE STRUCTURE		
<u>4,985,676</u>	<u>Karasawa; 1/91</u>	<u>324/158 R</u>
METHOD AND APPARATUS OF PERFORMING PROBING TEST FOR		
ELECTRICALLY AND SEQUENTIALLY TESTING SEMICONDUCTOR DEVICE		
PATTERNS		
<u>4,965,515</u>	<u>Karasawa; 10/90</u>	<u>324/158 R</u>
APPARATUS AND METHOD OF TESTING A SEMICONDUCTOR WAFER		
<u>4,950,982</u>	<u>Obikane et al.; 8/90</u>	<u>324/158 F</u>
ELECTRIC PROBING TEST MACHINE		

<u>4,943,767</u>	<u>Yokota; 7/90</u>	<u>324/158 F</u>
AUTOMATIC WAFER POSITION ALIGNING METHOD FOR WAFER PROBER		
<u>4,901,011</u>	<u>Koike et al.; 2/90</u>	<u>324/158 F</u>
CARRIER FOR TRANSFERRING PLATE-LIKE OBJECTS ONE BY ONE, A HANDLING APPARATUS FOR LOADING OR UNLOADING THE CARRIER, AND A WAFER PROBING MACHINE FITTED WITH THE HANDLING APPARATUS FOR THE WAFER CARRIER		
<u>4,875,005</u>	<u>Terada et al.; 10/89</u>	<u>324/158 F</u>
MECHANISM FOR TURNING OVER A TEST HEAD OF A WAFER PROBING MACHINE		
<u>4,604,910</u>	<u>Chadwick et al.; 8/86</u>	<u>74/96</u>
APPARATUS FOR ACCURATELY POSITIONING AN OBJECT AT EACH OF TWO LOCATIONS		
<u>4,123,706</u>	<u>Roch; 10/78</u>	<u>324/158 P</u>
PROBE CONSTRUCTION		
<u>4,056,777</u>	<u>Roch; 11/77</u>	<u>324/158 P</u>
MICROCIRCUIT TEST DEVICE WITH MULTI-AXES PROBE CONTROL		
<u>4,034,293</u>	<u>Roch; 7/77</u>	<u>324/158 P</u>
MICRO-CIRCUIT TEST PROBE		
<u>4,001,685</u>	<u>Roch; 1/77</u>	<u>324/158 P</u>
MICRO-CIRCUIT TEST PROBE		
<u>3,940,676</u>	<u>Dudley; 2/76</u>	<u>318/612</u>
DAMPING CONTROL FOR POSITIONING APPARATUS		
<u>3,939,414</u>	<u>Roch; 2/76</u>	<u>324/158 F</u>
MICRO-CIRCUIT TEST APPARATUS		

GROUP 2  
REFERENCES HAVING GENERAL INTEREST

\_\_\_ Copies of the references cited herein are enclosed herewith.

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 [C-7-US]

5,570,032      Atkins, et al.; 10/96      324/760  
WAFER SCALE BURN-IN APPARATUS AND PROCESS

5,532,610      Tsujide, et al.; 7/96      324/757  
APPARATUS FOR TESTING SEMICONDUCTOR WAFER

5,497,079      Yamada, et al.; 3/96      324/158.1  
SEMICONDUCTOR TESTING APPARATUS, SEMICONDUCTOR TESTING CIRCUIT CHIP, AND PROBE CARD

5,434,513      Fujii, et al.; 7/95      324/765  
SEMICONDUCTOR WAFER TESTING APPARATUS USING INTERMEDIATE SEMICONDUCTOR WAFER

5,073,117      Malhi, et al.; 12/91      439/71  
FLIP-CHIP SOCKET ADAPTOR AND METHOD

4,899,107      Corbett, et al.; 2/90      324/158F  
DISCRETE DIE BURN-IN FOR NONPACKAGED DIE

GROUP 3  
INTERFACES BETWEEN THE WAFER AND THE TESTER

\_\_\_ Copies of the references cited herein are enclosed herewith.

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 [C-7-US]

3A. Of seemingly greater relevance

5,070,297      Kwon, et al.; 12/91      324/158 P  
FULL WAFER INTEGRATED CIRCUIT TESTING DEVICE

5,457,400      Ahmad, et al.; 10/95      324/763  
SEMICONDUCTOR ARRAY HAVING BUILT-IN TEST CIRCUIT FOR WAFER LEVEL TESTING

5,397,997      Tuckerman, et al.; 3/95      324/754  
BURN-IN TECHNOLOGIES FOR UNPACKED INTEGRATED CIRCUITS

5,461,328      Devereaux, et al.; 10/95      324/765  
FIXTURE FOR BURN-IN TESTING OF SEMICONDUCTOR WAFERS

5,446,395      Goto; 8/95      324/763  
TEST CIRCUIT FOR LARGE SCALE INTEGRATED CIRCUITS ON A WAFER

5,483,175      Ahmad, et al.; 1/96      324/766  
METHOD FOR CIRCUITS CONNECTION FOR WAFER LEVEL BURNING AND TESTING OF INDIVIDUAL DIES ON SEMICONDUCTOR WAFER

5,336,992      Saito, et al.; 8/94      324/754  
ON-WAFER INTEGRATED CIRCUIT ELECTRICAL TESTING

5,532,614      Chiu; 7/96      324/763  
WAFER BURN-IN AND TEST SYSTEM

5,055,780      Takagi, et al.; 10/91      324/158  
PROBE PLATE USED FOR TESTING A SEMICONDUCTOR DEVICE, AND A TEST APPARATUS THEREFOR

5,047,711      Smith, et al.; 9/91      324/158R  
WAFER-LEVEL BURN-IN TESTING OF INTEGRATED CIRCUITS

5,440,241      King, et al.; 8/95      324/765  
METHOD FOR TESTING, BURNING-IN, AND MANUFACTURING WAFER SCALE INTEGRATED CIRCUITS AND A PACKAGED WAFER ASSEMBLY PRODUCED THEREBY

3B. Of seemingly lesser relevance

5,479,109      Lau, et al.; 12/95      324/758  
TESTING DEVICE FOR INTEGRATED CIRCUITS ON WAFER

5,444,386      Mizumura; 8/95      324/754  
PROBING APPARATUS HAVING AN AUTOMATIC PROBE CARD INSTALL  
MECHANISM AND A SEMICONDUCTOR WAFER TESTING SYSTEM INCLUDING  
THE SAME

5,442,282      Rostoker, et al.; 8/95      324/158.1  
TESTING AND EXERCISING INDIVIDUAL, UNSINGULATED DIES ON A  
WAFER

5,391,984      Worley; 2/95      324/158.1  
METHOD AND APPARATUS FOR TESTING INTEGRATED CIRCUIT DEVICES

5,363,038      Love; 11/94      324/158.1  
METHOD AND APPARATUS FOR TESTING AN UNPOPULATED CHIP CARRIER  
USING A MODULE TEST CARD

4,038,599      Bove, et al.; 7/77      324/158 F  
HIGH DENSITY WAFER CONTACTING AND TEST SYSTEM

3,849,872      Hubacher; 11/74      29/574  
CONTACTING INTEGRATED CIRCUIT CHIP TERMINAL THROUGH THE  
WAFER

GROUP 4: Flat Probes

\_\_\_ Copies of the references cited herein are enclosed herewith.

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 [C-7-US]

4A. Of seemingly greater relevance

5,555,422            Nakano; 9/96            324/754  
PROBER FOR SEMICONDUCTOR INTEGRATED CIRCUIT ELEMENT WAFER

5,517,126            Yamaguchi; 5/96            324/758  
PROBE APPARATUS

5,444,366            Chiu; 8/95            324/158.1  
WAFER BURN-IN AND TEST SYSTEM

5,510,724            Itoyama, et al.; 4/96            324/760  
PROBE APPARATUS AND BURN-IN APPARATUS

5,559,446            Sano; 9/96            324/760  
PROBING METHOD AND DEVICE

5,389,873            Ishii, et al.; 2/95            324/158.1  
PRESSURE CONTACT CHIP AND WAFER TESTING DEVICE

5,550,482            Sano; 8/96            324/758  
PROBE DEVICE

5,424,651            Green, et al.; 6/95            324/754  
FIXTURE FOR BURN-IN TESTING OF SEMICONDUCTOR WAFERS, AND A SEMICONDUCTOR WAFER

4B. Of seemingly lesser relevance

5,585,737            Shibata            324/754  
SEMICONDUCTOR WAFER PROBING METHOD...

5,534,784            Lum, et al.; 7/96            324/757  
METHOD FOR PROBING A SEMICONDUCTOR WAFER

5,506,498            Anderson, et al.; 4/96            324/158.1  
PROBE CARD SYSTEM AND METHOD

5,436,571            Karasawa; 7/95            324/765  
PROBING TEST METHOD OF CONTACTING A PLURALITY OF PROBES OF A PROBE CARD WITH PADS ON A CHIP ON A SEMICONDUCTOR WAFER

5,338,223            Melatti, et al.; 8/94            439/482  
HYBRID WAFER PROBE

5,220,277      Reitinger; 6/93      324/158 F  
ARRANGEMENT FOR TESTING SEMICONDUCTOR WAFERS OR THE LIKE

5,1330,644      Ott; 7/92      324/58 F  
INTEGRATED CIRCUIT SELF-TESTING DEVICE AND METHOD

4,961,052      Tada, et al.; 10/90      324/158 P  
PROBING PLATE FOR WAFER TESTING

4,899,099      Mendenhall, et al.; 2/90      324/158 F  
FLEX DOT WAFER PROBE

4,780,836      Miyazaki, et al.; 10/88      364/551.01  
METHOD OF TESTING SEMICONDUCTOR DEVICES USING A PROBE CARD

4,727,3319      Shahriary; 2/88      324/158 P  
APPARATUS FOR ON-WAFER TESTING OF ELECTRICAL CIRCUITS

GROUP 5: Temperature-controlled or flat chucks

     Copies of the references cited herein are enclosed herewith.

  x   Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 [C-7-US]

5A. Of seemingly greater relevance

5B. Of seemingly lesser relevance

5,532,609            Harwood, et al.; 7/96            324/754  
WAFER PROBE STATION HAVING ENVIRONMENT CONTROL ENCLOSURE

5,457,398            Schwindt, et al.; 10/95            324/754  
WAFER PROBE STATION HAVING FULL GUARDING

5,325,052            Yamashita; 6/94            324/158 P  
PROBE APPARATUS

5,303,938            Miller, et al.; 4/94            279/3  
KELVIN CHUCK APPARATUS AND METHOD OF MANUFACTURE

5,266,889            Harwood, et al.;            324/158 F  
WAFER PROBE STATION WITH INTEGRATED ENVIRONMENT CONTROL ENCLOSURE

5,198,752            Miyata, et al.; 3/93            324/158 F  
ELECTRIC PROBING-TEST MACHINE HAVING A COOLING SYSTEM



GROUP 6: Probe Structure or spring structure

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 **[C-7-US]**

6A. Of seemingly greater relevance

6B. Of seemingly lesser relevance

5,247,250 Rios; 9/93 324/158 F  
INTEGRATED CIRCUIT TEST SOCKET

5,214,375 Ikeuchi, et al.; 5/93 324/158 P  
MULTI-POINT PROBE ASSEMBLY FOR TESTING ELECTRONIC DEVICE

4,998,062      Ikeda; 3/91      324/158 F  
PROBE DEVICE HAVING MICRO-STRIP LINE STRUCTURE

4,985,676 Karasawa; 1/91 324/158 R  
METHOD AND APPARATUS OF PERFORMING PROBING TEST...

4,870,356      Tingley; 9/89      324/158 F  
MULTI-COMPONENT TEST STRUCTURE

4,523,144 Okubo, et al.; 6/85 324/158 P  
COMPLEX PROBE CARD FOR TESTING A SEMICONDUCTOR WAFER

GROUP 7: Other patents of interest

\_\_\_ Copies of the references cited herein are enclosed herewith.

x Copies of the references cited herein may be located in the file of commonly-owned, copending USSN 08/558,332 [C-7-US]

7A. Of seemingly greater relevance

5,534,786                      Kaneko, et al.; 7/96                      324/760  
BURN-IN AND TEST METHOD OF SEMICONDUCTOR WAFERS AND  
BURN-IN BOARDS FOR USE IN SEMICONDUCTOR WAFER BURN-IN TESTS

5,479,108                      Cheng; 12/95                      324/765  
METHOD AND APPARATUS FOR HANDLING WAFERS

7B. Of seemingly lesser relevance

5,568,056                      Ishimoto; 10/96                      324/754  
WAFER PROBER

5,559,444                      Farnworth, et al.; 9/96                      324/754  
METHOD AND APPARATUS FOR TESTING UNPACKAGED SEMICONDUCTOR DICE

5,488,292                      Tsuta; 1/96                      324/158.1  
WAFER INSPECTING SYSTEM

5,410,162                      Tigelaar, et al.; 4/95                      257/48  
APPARATUS FOR AND METHOD OF RAPID TESTING OF SEMICONDUCTOR  
COMPONENTS AT ELEVATED TEMPERATURE

5,355,081                      Nakata, et al.; 10/94                      324/765  
METHOD FOR TESTING A SEMICONDUCTOR INTEGRATED CIRCUIT HAVING  
SELF TESTING CIRCUIT

5,329,228                      Comeau; 7/94                      324/765  
TEST CHIP FOR SEMICONDUCTOR FAULT ANALYSIS

5,187,020                      Kwon, et al.; 2/93                      428/601  
COMPLIANT CONTACT PAD

5,140,405                      King, et al.; 8/92                      357/67  
SEMICONDUCTOR ASSEMBLY UTILIZING ELASTOMERIC SINGLE AXIS  
CONDUCTIVE INTERCONNECT

4,764,723                      Strid; 8/88                      324/158 P  
WAFER PROBE

4,746,857      Sakai, et al.; 5/88      324/158 F  
PROBING APPARATUS FOR MEASURING ELECTRICAL CHARACTERISTICS OF  
SEMICONDUCTOR DEVICE FORMED ON WAFER

4,697,143      Lockwood, wt al.; 9/87      324/158 P  
WAFER PROBE

4,567,433      Ohkubo, et al.; 1/86      324/158 P  
COMPLEX PROBE CARD FOR TESTING A SEMICONDUCTOR WAFER